

| Electronic Patent Application Fee Transmittal | | | | |
|---|---|----------|--------|----------------------|
| Application Number: | 10519699 | | | |
| Filing Date: | 14-Sep-2005 | | | |
| Title of Invention: | Ion implantation device and a method of semiconductor manufacturing by the implantation of boron hydride cluster ions | | | |
| First Named Inventor/Applicant Name: | Thomas N. Horsky | | | |
| Filer: | John S. Paniaguas/Anna Franz | | | |
| Attorney Docket Number: | 211843-00032 | | | |
| Filed as Large Entity | | | | |
| U.S. National Stage under 35 USC 371 Filing Fees | | | | |
| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
| Basic Filing: | | | | |
| Pages: | | | | |
| Claims: | | | | |
| Miscellaneous-Filing: | | | | |
| Petition: | | | | |
| Patent-Appeals-and-Interference: | | | | |
| Post-Allowance-and-Post-Issuance: | | | | |
| Extension-of-Time: | | | | |

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
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| Miscellaneous: | | | | |
| Request for continued examination | 1801 | 1 | 810 | 810 |
| Total in USD (\$) | | | | 810 |